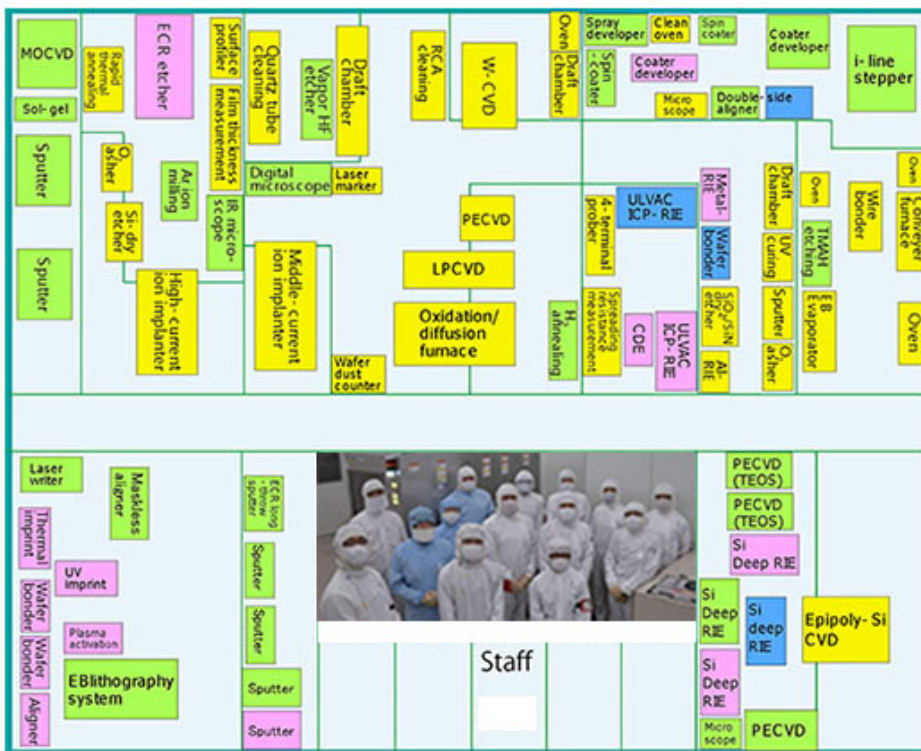


1 Hands-on-access fab. (Prof. K. Totsu)

Shared facility for industry to prototype MEMS devices (4 / 6 inch). Companies which cannot prepare their own facility dispatch their employees to operate equipments by themselves. The facility is located in 1800m² clean room, which was used for the production of power transistor and newly installed MEMS fabrication equipments. <http://www.mu-sic.tohoku.ac.jp/coin/index.html>

Contact person: Professor Kentaro Totsu Phone 022-229-4113, totsu@mems.mech.tohoku.ac.jp



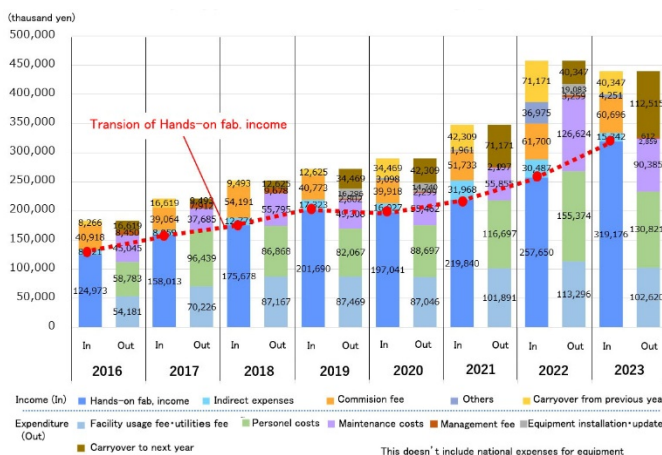
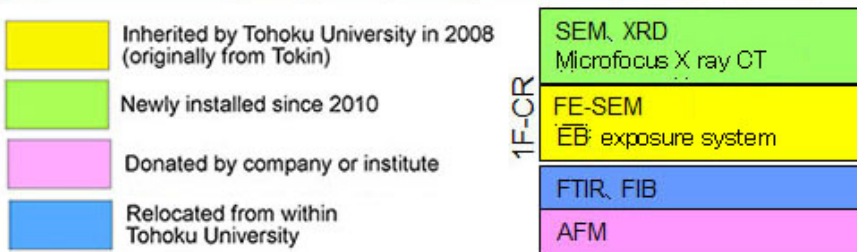
Patterning (I line stepper)



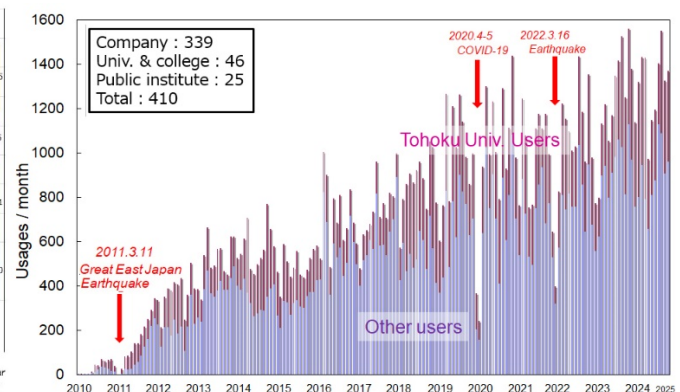
Oxidation, diffusion



Dry etching (DRIE)



Transition of income and expenditures



Transition of user number